

**PATENT NUMBER and  
ISSUE DATE**

**U.S. UTILITY Patent Application**

APPL NUM 10054962	FILING DATE 01/25/2002	CLASS 438	SUBCLASS 692	GAU 1765	EXAMINER UIC-6407, K
<b>**APPLICANTS:</b> Su Chun-Lien; Chin Chi-Yuan; Cho Shih-Keng; Chen Ming-Shang; Lin Yih-Shi;					
<b>**CONTINUING DATA VERIFIED:</b>					
<b>** FOREIGN APPLICATIONS VERIFIED:</b>					
PG-PUB <input type="checkbox"/> DO NOT PUBLISH <input type="checkbox"/>		RESCIND <input type="checkbox"/>			
Foreign priority claimed <input type="checkbox"/> yes <input type="checkbox"/> no		35 USC 119 conditions met <input type="checkbox"/> yes <input type="checkbox"/> no		ATTORNEY DOCKET NO 4006-150	
Verified and Acknowledged Examiners's initials					
<b>TITLE :</b> Method for controlling and monitoring a chemical mechanical polishing process <small>U.S. DEPT. OF COMM. / PAT. &amp; TM. PTO-436 (Rev. 12-94)</small>					

<b>NOTICE OF ALLOWANCE MAILED</b>		<b>CLAIMS ALLOWED</b>	
		Total Claims	Print Claim for O.O.
Assistant Examiner			
<b>ISSUE FEE</b>		<b>DRAWING</b>	
Amount Due	Date Paid	Sheets Drawg.	Figs. Drawg.
		Print Fig.	
<input type="checkbox"/> <b>TERMINAL</b> <b>DISCLAIMER</b> <b>BEST AVAILABLE</b>		Primary Examiner Application Examiner	
<input type="checkbox"/> <b>PREPARED FOR ISSUE</b>		WARNING: The information disclosed herein may be restricted. Unauthorized disclosure may be prohibited by the United States Code Title 35, Sections 122, 181 and 368. Possession outside the U.S. Patent & Trademark Office is restricted to authorized employees and contractors only.	

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